# Cascade PAV200

# 200 mm Semi-automated Vacuum Probe System

#### **>** Overview

Cascade PAV200 probe system from FormFactor is the ideal solution for automatic testing of wafers and substrates up to 200 mm in a high vacuum environment  $< 1 \times 10^{-4}$  mbar. It supports a wide temperature range from -60°C to 300°C.

It supports a wide range of applications, including DC and RF measurements, MEMS and opto-engineering tests. The probe platen is designed to mount probe cards or up to eight vacuum-type positioners on magnetic feet. A high-resolution video microscope with 50 mm x 50 mm travel range is mounted either on a microscope mount with swivel or on a microscope bridge for vibrationsensitive test applications and additional test instruments.



The PAV200 is equipped with a stable vibration isolating frame. The chuck and the motorized chuck stage with 200 mm x 200 mm X-Y travel, theta and Z-axis are located inside the high-vacuum chamber. Up to eight vacuum-type positioners can be easily operated from outside of the chamber via vacuum-tight mechanical feedthrough drives and cardan shafts. For the use under vacuum conditions, specially-designed thermal chucks with electrical and cooling line bulk-feedthroughs are available.

#### > Features / Benefits

Flexibility	• Different substrate carriers for wafers up to 200 mm or single dies
	<ul> <li>Upstream pressure, downstream pressure or medium vacuum regulation</li> </ul>
	<ul> <li>Velox<sup>™</sup> probe station control software</li> </ul>
	• Wide range of measurements (I-V, C-V, two-port, multi-port and differential RF)
	• RF tests supported by a wide range of probes and calibration tools, such as calibration substrates and WinCal XE™ calibration software
	<ul> <li>Accessories available, such as Black Bodies and optical motion analysis tools</li> </ul>
Stability	High accuracy, ideal for small structures
	Highly stable mechanics with a stable vibration isolation table
Ease of use	Simple, straightforward design for easy and ergonomic operation
	<ul> <li>Quick and ergonomic change of the DUT through front door</li> </ul>
Automation	Pressure control: up-stream, down-stream, high-precision capacitance vacuum gauges
	Bridge with rails for programmable movement of mounted instruments
High measurement	<ul> <li>Automatic control of chuck for fast step-and-repeat testing of the entire wafer throughput</li> </ul>



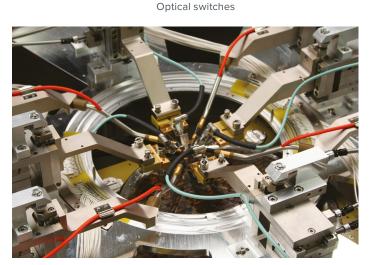
## **>** Applications

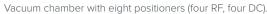
MEMS Acceleration sensors

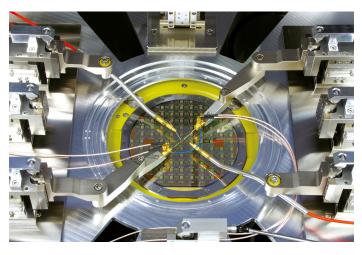
RF MEMS switches Micro-bolometers Gyro sensors Gas sensors

Pressure sensors

MOEMS Micro-mirrors







Vacuum chamber with four DC positioners.

## > Vacuum Probecard

Vacuum Probecard

Customer electronics on board possible

Easy-to-use probecard holder for fast change of probe card

Needle ring for up to 120 needles

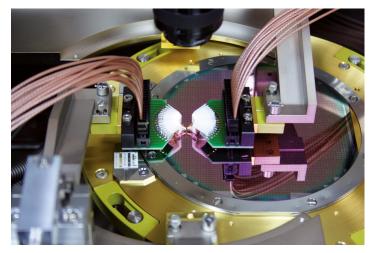
Coax and/or twisted-pair cabling

Pseudo Kelvin cabling – junction point at probecard holder

Alternatively, DC ProbeWedges $^{\text{\tiny{TM}}}$  can be used



Vaccum probe card.



Two DC ProbeWedges on positioners.



#### > Handling





Probe positioning.

Wafer loading principle.

#### > Integration of Third-Party MEMS Test Tools

Polytec MSA-500 For out-of-plane and in-plane motion analysis and optional topology measurements

Seamless integration of both systems by Cascade Microtech and Polytec Communication Tool

Black bodies For controlled exposure with infrared radiation for microbolometer testing

Cavity or surface type can be adopted

Aperture, filter and shutter functions are optionally available



Polytec MSA-500 over topside viewport for mechanical motion analysis.



PAV200 with Black Body for microbolometer testing.

© Copyright 2022 FormFactor, Inc. All rights reserved. FormFactor and the FormFactor logo are trademarks of FormFactor, Inc. All other trademarks are the property of

All information is subject to change without notice.

PAV200-DS-0722

#### **Corporate Headquarters**

7005 Southfront Road Livermore, CA 94551 Phone: 925-290-4000 www.formfactor.com

